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(54) Title: SEMICONDUCTOR PROCESSING APPARATUS HAVING WAFER RE-ORIENTATION MECHANISM

(57) Abstract

A semiconductor processing apparatus is set forth. The processing apparatus includes an input section (12) having an opening (32) through which a carrier (16) supporting a plurality of semiconductor wafers (W) is inserted. The semiconductor wafers are oriented in a generally vertical state when the carrier is inserted through the opening of the input section. An orientation changing apparatus (40) is disposed to accept the carrier with the semiconductor wafers in the generally vertical state. The orientation changing apparatus re-orients the carrier so that the wafers are re-oriented in a generally horizontal state. The processing apparatus further includes a processing section (14) having a plurality of processing stations (20, 22) for processing the semiconductor wafers and a transfer apparatus (62) disposed to accept the semiconductor wafers in the generally horizontal state. The transfer apparatus accepts the wafers and provides them to one or more of the processing stations in the processing section.

